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PATENT NUMBER and
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U.S. UTILITY Patent Application

APPL NUM 10030657	FILING DATE 01/11/2002	CLASS 371	SUBCLASS 402	GAUS 1765	EXAMINER Le
**APPLICANTS: Wakamatsu Satoru; Oda Hiroyuki; 1773					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP01/03865 05/09/2001					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-139023 05/11/2000					
PG-PUB		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO 1691-0170P	
TITLE : Polycrystalline silicon and process and apparatus for producing the same					

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

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NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	Total Claims
			Print Claim for O.G.
ISSUE FEE			DRAWING
Amount Due	Date Paid		Sheets Drwg.
			Figs. Drwg.
			Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner	Application Examiner
		PREPARED FOR ISSUE	
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